

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant	:	Hojo et al.
Appl. No.	:	10/554,380
Filed	:	October 26, 2005
For	:	POSITIVE PHOTORESIST COMPOSITION AND METHOD FOR FORMING RESIST PATTERN
Examiner	:	A. Eoff
Group Art Unit	:	1753

**AMENDMENT AND RESPONSE TO OFFICE ACTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed **September 10, 2007**, Applicants respectfully request the Examiner to enter the following amendments and consider the following remarks.

**Amendments to the claims** are reflected in the **listing of claims** which begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.